Supporting Information

for

Oxidative chemical vapor deposition of polyaniline thin films

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Additional data

Scanning Electron Microscopy

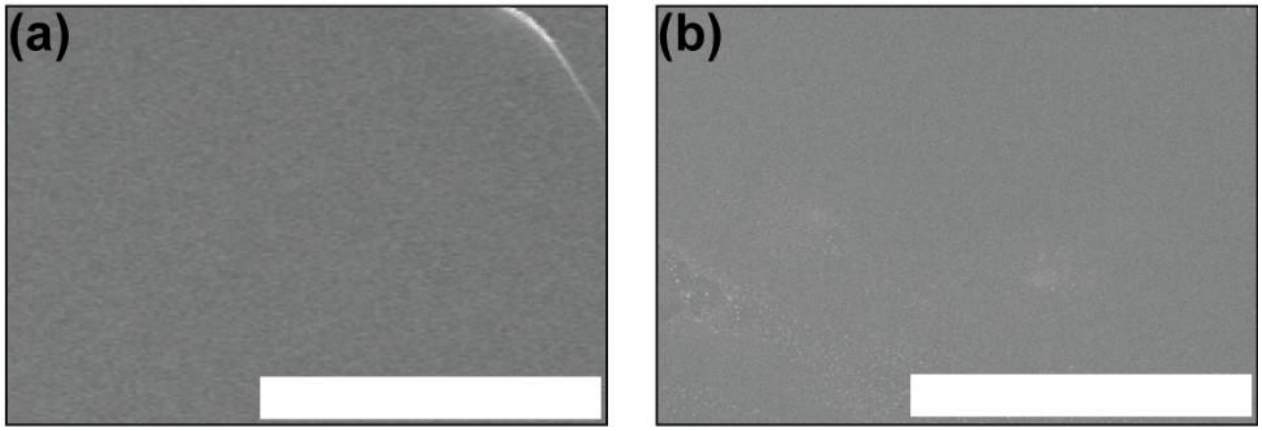

Figure S1: Top-down SEM of (a) as-deposited, and (b) THF-washed oCVD PANI films at lower magnification. Scale bar is 10 µm.

Fourier Transform Infrared Spectroscopy

Table S1: Major FTIR peak positions and assignments for oCVD PANI.

Peak Position (cm^{-1})	Peak Assignment	Reference (in main paper)
3304	NH stretch	[44-46]
3100–3000	CH stretch	[44-46]
1168–1160	$–NH^{+}=$ stretch / CH vibration	[46,47]
865–821	CH vibration (out-of-plane)	[47-49]
1588–1577	Quinoid ring stretch	[50,51]
1510–1490	Benzenoid ring stretch	[50,51]
1382	CN stretch of quinoid ring	[50]
1635	NH scissoring vibration of aromatic amines	[52]
749	CH out-of-plane bending	[48]
688	CH out-of-plane ring deformation	[48]

X-ray Photoelectron Spectroscopy

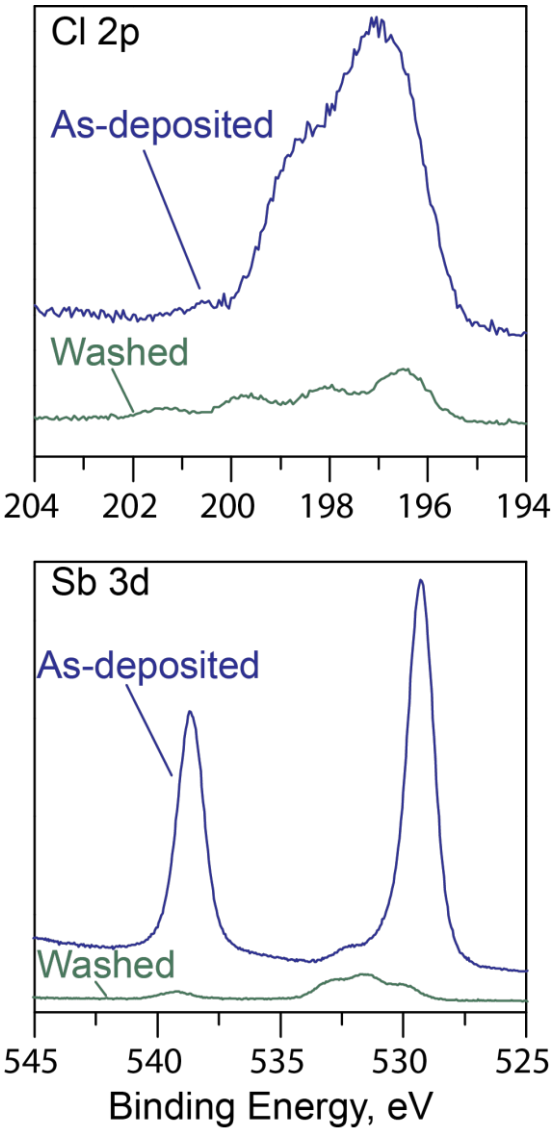

Figure S2: High-resolution Cl2p (top) and Sb3d (bottom) XPS spectra of as-deposited (blue) and washed (green) oCVD PANI films.